

at least two scanning beam focusing mechanisms each configured to bring the scanning light beam to a focus on a photoconductive surface, each of said at least two scanning beam focusing mechanisms satisfying an equation:

$\Delta L \cos \alpha > R/2$ at a junction of the at least two scanning light beams with each other on the photoconductive surface,

wherein ΔL represents an inherent light pass length variation, α represents an incident angle, and R represents an inherent marginal distance.

4. (Amended) The optical scanning apparatus, comprising:

at least two light source means for emitting a light beam;

at least two beam shaping means each for shaping the light beam;

light deflecting means for deflecting each light beam in a continuously changing direction thereby converting each light beam into a scanning light beam; and

at least two scanning beam focusing means each for bringing the scanning light beam to a focus on a photoconductive surface, each of said at least two scanning beam focusing means satisfying an equation:

$\Delta L \cos \alpha > R/2$ at a junction of the at least two scanning light beams with each other on the photoconductive surface,

wherein ΔL represents an inherent light pass length variation, α represents an incident angle, and R represents an inherent marginal distance.

7. (Amended) A method of optical scanning, comprising the steps of:

emitting at least two light beams;

shaping said at least two light beams;

deflecting each of said at least two light beams in a continuously changing direction so as to convert each of said at least two light beams into a scanning light beam; and